

***Amendments to the Specification***

Please replace paragraph [0012] of the specification with the following paragraph:

**[0012]** In a vacuum deposition apparatus with such a composition, the robot arm 8 is used to transfer the preheated glass substrate 4 from a heat chamber (not shown) to the process chamber 2. After moving to the process chamber 2, the robot arm 8 moves forward in the advancing direction as shown in Fig. 2, to have the glass substrate 4 positioned at the top of the susceptor 10. In this case, the robot arm 8 moves up to a home position and the time belt 14 is driven for the amount of time needed to position the susceptor 10 and the lift pin 6 so that they do not interfere with the robot arm 8. In this way the susceptor 10 is moved up to a load position after the glass substrate 4 is positioned at the top of the susceptor 10 by the robot arm 8, so that the glass substrate 4 is supported by the lift pin 6. ~~When this occurs the robot arm 8 is in contact with both the glass substrate 4 and the susceptor 10.~~

Please replace paragraph [0016] of the specification with the following paragraph:

**[0016]** Also, the robot arm 8 is inclined at around 85 degrees when it moves forward to place the glass substrate 4 on the surface of the susceptor 10. Due to the incline, ~~a leading edge of friction between the glass substrate scrapes film~~

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~~forming material from the surface of and~~ the susceptor 10 and causes ~~film-~~  
~~forming~~ the material to collect on ~~[[the]]~~ a portion of the susceptor 10 where  
sliding the glass substrate ~~occurs~~ pushes it.